

EAST Search History

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|---|------------------|---------|------------------|
| S1 | 6 | ("4890245" "5154512" "5508934" "5994676" "6171641" "6204484").PN. | US-PGPUB; USPAT | OR | ON | 2006/03/23 14:08 |
| S2 | 2467 | wafer with calibration | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 11:38 |
| S3 | 4 | S2 and semiconductor and implant\$5 and (coat\$3 with cobalt) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 14:41 |
| S4 | 4 | S2 and semiconductor and (coat\$3 with cobalt) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 11:42 |
| S5 | 494 | wafer and (coat\$3 with cobalt) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 12:41 |
| S6 | 3 | S5 and emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 16:09 |
| S7 | 76 | cobalt with emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 17:07 |
| S8 | 1 | ("6171641").PN. | USPAT | OR | OFF | 2006/03/23 11:58 |
| S9 | 1 | ("5624590").PN. | USPAT | OR | OFF | 2006/03/23 12:39 |
| S10 | 37 | (lattice near2 defect) and emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 13:13 |

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| S11 | 2 | (lattice near2 defect) with emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 12:43 |
| S12 | 22 | (lattice adj defect) and emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 13:19 |
| S13 | 950 | thickness with emissivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 13:19 |
| S14 | 26 | S13 and (wafer adj thickness) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 13:19 |
| S15 | 1 | ("6072164").PN. | USPAT | OR | OFF | 2006/03/23 14:08 |
| S16 | 915 | calibration near2 wafer | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 14:42 |
| S17 | 31 | S16 and emissivity and (dop\$3 or implant\$5) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 14:42 |
| S18 | 839 | emissivity with reflectivity | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 16:09 |
| S19 | 123 | S18 and (silicon adj wafer) | US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2006/03/23 16:09 |
| S20 | 1 | ("4321299").PN. | USPAT | OR | OFF | 2006/03/23 17:07 |

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| S21 | 84 | (temperature with calibration).TI. | USPAT | OR | ON | 2006/09/05 14:59 |
| S22 | 2836 | 438/795.ccls. or 374/1,121,126,179. ccls. | US-PGPUB; USPAT | OR | ON | 2006/09/05 16:22 |
| S23 | 1053 | 438/795.ccls. | US-PGPUB; USPAT | OR | ON | 2006/09/05 15:47 |
| S24 | 67 | S22 and (calibration with wafer) | US-PGPUB; USPAT | OR | ON | 2006/09/05 15:01 |
| S25 | 1784 | 374/1,121,126,179.ccls. | US-PGPUB; USPAT | OR | ON | 2006/09/05 16:22 |

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| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|--|----------|------------------|---------|------------------|
| L1 | 0 | ((calibration with (wafer or substrate)) and reflecti\$6 and simulate\$3 and heat and radiation and temperature and (measur\$3 with temperature) and (measur\$3 with radiation) and parameter and calculat\$4 and correct\$4).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:53 |
| L2 | 0 | ((calibration with (wafer or substrate)) and reflecti\$6 and simulate\$3 and heat and radiation and temperature and (measur\$3 with temperature) and parameter and calculat\$4 and correct\$4).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:53 |
| L3 | 0 | ((calibration with (wafer or substrate)) and simulate\$3 and heat and radiation and temperature and (measur\$3 with temperature) and parameter and calculat\$4 and correct\$4).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:53 |
| L4 | 0 | ((calibration with (wafer or substrate)) and heat and radiation and temperature and (measur\$3 with temperature) and parameter and calculat\$4 and correct\$4).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:54 |
| L5 | 0 | ((calibration with (wafer or substrate)) and heat and radiation and temperature and (measur\$3 with temperature) and parameter and correct\$4).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:54 |
| L6 | 0 | ((calibration with (wafer or substrate)) and heat and radiation and temperature and (measur\$3 with temperature) and parameter).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:54 |
| L7 | 0 | ((calibration with (wafer or substrate)) and heat and radiation and temperature and parameter).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:54 |
| L8 | 2 | ((calibration with (wafer or substrate)) and heat and radiation and temperature).CLM. | US-PGPUB | OR | ON | 2006/09/06 11:55 |